



Attorney's Docket No.: 8034 USA/W-C/W-C/HMM

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Patent Application of:

Christopher Laurent Beaudry, et al.

Examiner: Duy V.N. Deo

Application No: 10/736,007

Art Unit: 1765

Filing Date: December 15, 2003

For: SINGLE WAFER CLEANING
METHOD TO REDUCE PARTICLE
DEFECTS ON A WAFER SURFACE

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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AMENDMENT AND RESPONSE

Dear Sir:

This is in response to the Office Action mailed April 6, 2006. Applicant respectfully requests the Examiner to enter the following amendments and consider the following remarks.:

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

on July 31, 2006

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